

Oral presentation | 21 Joint Session K | 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"

[18a-E201-1~11]21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"

Toshiyuki Kawaharamura(Kochi Univ. of Tech.)

Sun. Mar 18, 2018 9:00 AM - 12:15 PM E201 (57-201)

△：奨励賞エントリー

▲：英語発表

▼：奨励賞エントリーかつ英語発表

空欄：どちらもなし

9:00 AM - 9:30 AM

[18a-E201-1][The 8th Kashiko Kodate Award Speech] Insulating films contributing to high performance oxide semiconductor thin film transistors

○Mami N. Fujii¹ (1.NAIST)

Keywords:Insulating films